



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

MICHAEL FRIEDEMANN
VOLKER KAHLERT

Serial No.: 10/624,420

Filed: July 22, 2003

For: METHOD OF FORMING A
CONDUCTIVE BARRIER LAYER
HAVING IMPROVED COVERAGE
WITHIN CRITICAL OPENINGS

Group Art Unit: 1753

Examiner: Unknown

Att'y Docket: 2000.108100/DE0346

Customer No.: 23720

INFORMATION DISCLOSURE STATEMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

CERTIFICATE OF MAILING
37 C.F.R 1.8

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date below:

May 12, 2004

Date

Mary Paul

Signature

In compliance with the duty of disclosure under 37 C.F.R. § 1.56, it is respectfully requested that this Information Disclosure Statement be entered and the documents listed on attached Form PTO-1449 be considered by the Examiner and made of record. Because the filing date of the present application is after June 30, 2003, copies of the listed U.S. patents are not included.

In accordance with 37 C.F.R. §§ 1.97(g),(h), this Information Disclosure Statement is not to be construed as a representation that a search has been made, and is not to be construed to be an admission that the information cited is, or is considered to be, material to patentability as defined in 37 C.F.R. § 1.56(b).

In accordance with 37 C.F.R. § 1.97(e)(1), Applicants hereby certify that each item of information contained in this Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the present statement, as evidenced by the date of the enclosed letter from the German associate.

Applicants respectfully request that the listed documents be made of record in the present case.

Respectfully submitted,

WILLIAMS, MORGAN & AMERSON
CUSTOMER NO. 23720

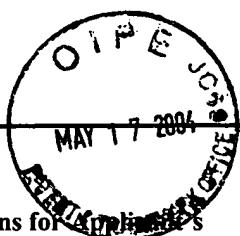


Date: May 12, 2004

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Form PTO-1449 (modified)



Atty. Docket No. 2000.108100/DE0346	Serial No. 10/624,420
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List of Patents and Publications for Application No. 10/624,420**INFORMATION DISCLOSURE STATEMENT**

(Use several sheets if necessary)

Filing Date: July 22, 2003	Group: 1753
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U.S. Patent Documents <i>See Page 1</i>	Foreign Patent Documents <i>See Page 1</i>	Other Art <i>See Page 1</i>
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U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
	A1	5,963,827	10/05/99	Enomoto <i>et al.</i>	438	629	
	A2	6,306,732 B1	10/23/01	Brown	438	468	
	A3	6,365,510	04/02/02	Schmidbauer <i>et al.</i>	438	675	
	A4	6,380,058 B2	04/30/02	Manabe <i>et al.</i>	438	597	
	A5						

Foreign Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Country	Class	Sub Class	Translation Yes/No
	B1	WO 03/001590 A2	1/03/03	PCT	H01L	21/768	Yes
	B2						
	B3						

Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
	C1	Rossnagel <i>et al.</i> , "Thin, high atomic weight refractory film deposition for diffusion barrier, adhesion layer, and seed layer applications," <i>J. Vac. Sci. Technol.</i> , 143:1819027, 1996
	C2	Zhong and Hopwood, "Ionized deposition into high aspect ratio vias and trenches," <i>J. Vac. Sci. Technol.</i> , 17:405-09, 1999
	C3	

EXAMINER:**DATE CONSIDERED:**

EXAMINER: INITIAL IF REFERENCE CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.